

020732-97.668 (7493)

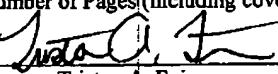
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re United States Patent Application of:)	Docket No.:	020732-97.668	
)		(7493)	
Applicants:	RATH, Melissa K., et al.)	Conf. No.:	4823
Application No.:	10/792,038)	Art Unit:	1752
Date Filed:	March 3, 2004)	Examiner:	LE, Hoa Van
Title:	COMPOSITION AND PROCESS FOR POST-ETCH REMOVAL OF PHOTORESIST AND/OR SACRIFICIAL ANTI-REFLECTIVE MATERIAL DEPOSITED ON A SUBSTRATE)	Customer No.:	24239

UNOFFICIAL FACSIMILE TRANSMISSION

Attn: Examiner Hoa Van Le
Fax No. (571) 273-1332

I hereby certify that this document is being filed in the United States Patent and Trademark Office, via facsimile transmission to Examiner Lee's personal facsimile number on October 31, 2006.

31	Number of Pages (including cover)
	
Tristan A. Fuierer	
October 31, 2006	
Date	

**RESUBMISSION OF THE RESPONSE TO AUGUST 30, 2006 OFFICE ACTION IN
UNITED STATES PATENT APPLICATION NO. 10/792,038**

Mail Stop Amendment
 Commissioner for Patents
 PO Box 1450
 Alexandria, VA 22313-1450

Sir:

Pursuant to a recent telephone call from Examiner Le, whereby he indicated that the USPTO only received 27 of the 30 pages of the response to the August 30, 2006 Office Action, applicants hereby resubmit said response. Applicants also submit that the original response to the Office Action did include all 30 pages, as indicated in the copy of the Auto-Reply certificate attached herewith in Appendix A.

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Please amend the claims, as set out in the following **Section I (the Claims)**.

Remarks addressing the substance of the August 30, 2006 Office Action are set out in the **Section II (Remarks)** hereof.